IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Priority Application Serial No	09/449,025
Priority Filing Date	November 24, 1999
Inventor	Shozo Nagano et al.
Assignee	Honeywell International, Inc.
Priority Group Art Unit	
Examiner	Unknown
Attorney's Docket No.	30-5000-(4015)-Div2
Title: Physical Vapor Deposition Targets	,

PRELIMINARY AMENDMENT

To: Box Patent Application

Assistant Commissioner for Patents

Washington, D.C. 20231

From: Mark S. Matkin (Tel. 509-624-4276; Fax 509-838-3424)

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Sir:

Please enter the following amendments prior to examining the aboveidentified application.

AMENDMENTS

In the Title

Please replace the title with the following: --PHYSICAL VAPOR DEPOSITION TARGETS.--

In The Specification

At page 1 before the "Technical Field" section, please insert the following:

-- RELATED PATENT DATA

This patent resulted from a divisional application of U.S. Patent Application Serial No. 09/449,025, filed November 24, 1999, entitled "Physical

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Vapor Deposition Targets, Conductive Integrated Circuit Metal Alloy Interconnects, Electroplating Anodes, and Metal Alloys For Use as a Conductive Interconnection in an Integrated Circuit", naming Shozo Nagano, Hinrich Hargarter, Jianxing Li and Jane Buehler as inventors, the disclosure of which is incorporated by reference.--

In the Claims

Cancel claims 1-16 and 21-59 without prejudice.

REMARKS

This application is a divisional application of U.S. Patent Application Serial No. 09/449,025. Original claims 1-16 and 21-59 have been canceled without prejudice. Claims 17-20 remain in the application for consideration.

Respectfully submitted,

Dated: 2 - 13 - 01

Mark S. Matkin Reg. No. 32,268